

Form PTO 1449  U.S. Department of Commerce Patent and Trademark Office  Information Disclosure Statement by Applicant	ATTY. DOCKET NUMBER <b>HITA.0501</b>	SERIAL NUMBER <b>To be assigned</b>
	APPLICANT <b>SAITO et al</b>	
	FILING DATE <b>Concurrently herewith</b>	GROUP

**U.S. Patent Documents**

Examiner Initial	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE

**Foreign Patent Documents**

Examiner Initial	DOCUMENT NUMBER	FILING DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
						YES	NO
<b>PC</b>	<b>2002-313951</b>	<b>4/11/2001</b>	<b>Japan</b>			<b>Abstract</b>	<b>X</b>

**Other Documents (Including Author, Title, Date Pertinent Pages, Etc.)**

<b>PC</b>	Digh Hisamoto, "FD/DG-SOI MOSFET - A Viable Approach to Overcoming the Device Scaling Limit", IEEE (2001), 4 pages
<b>PC</b>	Robert Chau et al., "30 nm Physical Gate Length CMOS Transistors with 1.0 ps n-MOS and 1.7 ps p-MOS Gate Delays", IEEE (2000), 4 pages
<b>PC</b>	Patrick P. Gelsinger, "Microprocessors for the New Millennium: Challenges, Opportunities, and New Frontiers", 2001 IEEE International Solid-State Circuits Conference, 10 pages
<b>PC</b>	D.A. Buchanan et al. "80 nm Poly-silicon Gated n-FETs with Ultra-Thin Al <sub>2</sub> O <sub>3</sub> Gate Dielectric for ULSI Applications", IEEE (2000), 4 pages
<b>PC</b>	K. Torii et al., "Fixed Charge-Induced Mobility Degradation and its Recovery in MISFET's with Al <sub>2</sub> O <sub>3</sub> Gate Dielectric", IWGI 2001, Tokyo, pp. 230-232
<b>PC</b>	K. Torii et al., "The Mechanism of Mobility Degradation in MISFETs with Al <sub>2</sub> O <sub>3</sub> Gate Dielectric", IEEE, 2002 Symposium on VLSI Technology Digest of Technical Papers, 2 pages
<b>PC</b>	K. Rim et al., "Mobility Enhancement in Strained Si NMOSFETs with HfO <sub>2</sub> Gate Dielectrics", IEEE, 2002 Symposium on VLSI Technology Digest of Technical Papers, 2 pages
<b>PC</b>	Kunihiro Suzuki et al., "Scaling Theory for Double-Gate SOI MOSFET's", IEEE Transactions on Electron Devices, Vol. 40, No. 12, December 1993, pp. 2326-2329
<b>PC</b>	International Technology Roadmap for Semiconductors, 2001 Edition, "Front End Processes", pp. 1-44

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